

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yuji IMAI

Application No.: Rule 53(b) Divisional of 09/839,202 filed April 23, 2001

Filed: March 4, 2004

Docket No.: 109325.01

For: METHOD FOR EVALUATING LITHOGRAPHY SYSTEM, METHOD FOR  
ADJUSTING SUBSTRATE-PROCESSING APPARATUS, LITHOGRAPHY  
SYSTEM, AND EXPOSURE APPARATUS

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Prior to initial examination on the merits, please consider the following:

**Amendments to the Specification; and**

**Remarks.**